) |.5.5.N. 10/044,014

Claim Amendments

Please amend claims 1 and 14 as follows.

1. (currently amended) An apparatus for transporting a semiconductor wafer to or from one position to another position a wafer cassette housing with increased damage resistance upon misalignment comprising:

an end effector having a base portion and at least one linger extending from the base portion, the finger having an uppermost top surface and a bottom surface and the to define the finger including a free end[[,]]; [[and]]

wherein the <u>uppermost</u> top surface includes a substantially flat portion extending from the base portion, and wherein the finger includes a tapered portion extending from the substantially flat portion towards bottom surface to define the free end; and,

wherein the tapered portion includes an angled surface formed at an angle ranging from about 2-8 degrees with respect to the substantially flat portion; and,

[[and]] wherein the thickness of the finger between the substantially flat portion [[of]] and the bottom surface ranges from about 1.0-1.95 mm 0.05-0.2 mm less than an opening defined between adjacently positioned wafers in the wafer cassette housing.